

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of	:	Attorney Docket No. 2005_1890A
Tetsuji TOGAWA et al.	:	Confirmation No. 7353
Serial No. 10/559,135	:	Group Art Unit 3723
Filed February 11, 2008	:	Examiner Eileen P. Morgan
SUBSTRATE POLISHING APPARATUS AND SUBSTRATE POLISHING METHOD	:	Mail Stop: RCE

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action of June 16, 2009, the period for response having been extended by one month to October 16, 2009, please amend the above-identified U.S. Patent application as follows.